SHIGA7.046APC PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

Ando et al.

Appl. No.

10/572,709 : March 17, 2006

Filed For

POSITIVE RESIST

COMPOSITION AND RESIST LAMINATE FOR OW-ACCELERATION ELECTRON BEAM AND METHOD OF

PATTERN FORMATION

Examiner

Schilling, R.

Group Art Unit 1795 CERTIFICATE OF FES WEB TRANSMISSION

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RESPONSE TO RESTRICTION REQUIREMENT

Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir-

In the Restriction/Election requirement mailed February 19, 2008, the Examiner restricted the pending claims into three patentably distinct inventions

- 1. Claims 1-20, drawn to compositions, classified in class 430, subclass 270.1;
- II. Claims 21-39, drawn to image resist laminates, classified in class 430, subclass 14: and
- III. Claims 40-43, drawn to electron beam exposure, classified in class 430, subclass 296.

In response to the Restriction Requirement, Applicants hereby elect Group I (Claims 1-20), without traverse. Thus, claims 1-20 encompass the elected invention. Applicants reserve the right to pursue the remaining invention(s) in a divisional application(s).

Appl. No. : 10/572,709 Filed : March 17, 2006

No fees are believed to be due. However, please charge any additional fees, including any fees for additional extension of time, or credit overpayment to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 3/5/08

By:

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